HS Code	Product Description	Base Rate	Year 1	Year 2	Year 3	Year 4	Year 5	Year 6	Year 7	Year 8	Year 9	Year 10	Year 11	Year 12	Year 13	Year 14	Year 15	Year 16	Year 17	Year 18	Year 19	Year 20 and Subsequent Years
8483.50.00	- Flywheels and pulleys, including pulley blocks	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8483.60.00	- Clutches and shaft couplings (including universal joints)	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90	**- Toothed wheels, chain sprockets and other transmission elements presented separately; parts:**																					
8483.9	**- - Parts of goods of subheading 8483.10:**																					
8483.90.11	- - - For tractors of subheading 8701.10 or 8701.90	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90.13	- - - For other tractors of heading 87.01	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90.14	- - - For goods of heading 87.11	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90.15	- - - For other goods of Chapter 87	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90.19	- - - Other	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8483.9	**- - Other:**																					
8483.90.91	- - - For goods of subheading 8701.10 or 8701.90	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90.93	- - - For other tractors of heading 87.01	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90.94	- - - For goods of heading 87.11	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90.95	- - - For other goods of Chapter 87	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8483.90.99	- - - Other	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
84.84	**Gaskets and similar joints of metal sheeting combined with other material or of two or more layers of metal; sets or assortments of gaskets and similar joints, dissimilar in composition, put up in pouches, envelopes or similar packings; mechanical seals.**																					
8484.10.00	- Gaskets and similar joints of metal sheeting combined with other material or of two or more layers of metal	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8484.20.00	- Mechanical seals	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8484.90.00	- Other	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
84.86	**Machines and apparatus of a kind used solely or principally for the manufacture of semiconductor boules or wafers, semiconductor devices, electronic integrated circuits or flat panel displays; machines and apparatus specified in Note 9 (C) to this Chapter; parts and accessories.**																					
8486.10	**- Machines and apparatus for the manufacture of boules or wafers:**																					
8486.10.10	- - Apparatus for rapid heating of semiconductor wafers	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8486.10.20	- - Spin dryers for semiconductor wafer processing	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.10.30	- - Machines for working any material by removal of material, by laser or other light or photon beam in the production of semiconductor wafers	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.10.40	- - Machines and apparatus for sawing monocrystal semiconductor boules into slices, or wafers into chips	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8486.10.50	- - Grinding, polishing and lapping machines for processing of semiconductor wafers	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.10.60	- - Apparatus for growing or pulling monocrystal semiconductor boules	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.10.90	- - Other	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20	**- Machines and apparatus for the manufacture of semiconductor devices or of electronic integrated circuits:**																					
8486.2	**- - Film formation equipment:**																					
8486.20.11	- - - Chemical vapour deposition apparatus for semiconductor production	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.12	- - - Epitaxial deposition machines for semiconductor wafers; spinners for coating photographic emulsions on semiconductor wafers	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.20.13	- - - Apparatus for physical deposition by sputtering on semiconductor wafers; physical deposition apparatus for semiconductor production	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.19	- - - Other	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.2	**- - Doping equipment:**																					
8486.20.21	- - - Ion implanters for doping semiconductor materials	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.29	- - - Other	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.2	**- - Etching and stripping equipment:**																					
8486.20.31	- - - Deflash machines for cleaning and removing contaminants from the metal leads of semiconductor packages prior to the electroplating process; spraying appliances for etching, stripping or cleaning semiconductor wafers	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.20.32	- - - Equipment for dry-etching patterns on semiconductor materials	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.33	- - - Apparatus for wet etching, developing, stripping or cleaning semiconductor wafers	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.39	- - - Other	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.2	**- - Lithography equipment:**																					
8486.20.41	- - - Direct write-on-wafer apparatus	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.20.42	- - - Step and repeat aligners	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.20.49	- - - Other	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.2	**- - Equipment for developing exposed wafers:**																					
8486.20.51	- - - Dicing machines for scribing or scoring semiconductor wafers	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.59	- - - Other	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8486.2	**- - Other:**																					
8486.20.91	- - - Lasercutters for cutting contacting tracks in semiconductor production by laser beam	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%

HS Code	Product Description	Base Rate	Year 1	Year 2	Year 3	Year 4	Year 5	Year 6	Year 7	Year 8	Year 9	Year 10	Year 11	Year 12	Year 13	Year 14	Year 15	Year 16	Year 17	Year 18	Year 19	Year 20 and Subsequent Years
8486.20.92	- - - Machines for bending, folding and straightening semiconductor leads	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.93	- - - Resistance heated furnaces and ovens for the manufacture of semiconductor devices on semiconductor wafers	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.20.94	- - - Inductance or dielectric furnaces and ovens for the manufacture of semiconductor devices on semiconductor wafers	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8486.20.95	- - - Automated machines for the placement or the removal of components or contact elements on semiconductor materials	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.20.99	- - - Other	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.30	**- Machines and apparatus for the manufacture of flat panel displays:**																					
8486.30.10	- - Apparatus for dry etching patterns on flat panel display substrates	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.30.20	- - Apparatus for wet etching, developing, stripping or cleaning flat panel displays	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.30.30	- - Chemical vapour deposition apparatus for flat panel display production; spinners for coating photosensitive emulsions on flat panel display substrates; apparatus for physical deposition on flat panel display substrates	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.30.90	- - Other	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40	**- Machines and apparatus specified in Note 9 (C) to this Chapter:**																					
8486.40.10	- - Focused ion beam milling machines to produce or repair masks and reticles for patterns on semiconductor devices	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.20	- - Die attach apparatus; tape automated bonders, wire bonders and encapsulation equipment for the assembly of semiconductors; automated machines for transport, handling and storage of semiconductor wafers, wafer cassettes, wafer boxes and other materials for semiconductor devices	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.40.30	- - Moulds for manufacture of semiconductor devices	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.40	- - Optical stereoscopic microscopes fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.50	- - Photomicrographic microscopes fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.60	- - Electron beam microscopes fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.70	- - Pattern generating apparatus of a kind used for producing masks or reticles from photoresist coated substrates	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.40.90	- - Other	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.90	**- Parts and accessories:**																					
8486.9	**- - Of machines and apparatus for the manufacture of boules or wafers:**																					
8486.90.11	- - - Of apparatus for rapid heating of semiconductor wafers	5%	5%	5%	5%	5%	5%	3%	3%	3%	3%	2%	2%	2%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.12	- - - Of spin dryers for semiconductor wafer processing	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.13	- - - Of machines for working any material by removal of material, by laser or other light or photon beam in the production of semiconductor wafers	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.9	**- - - Of machines for sawing monocrystal semiconductor boules into slices, or wafers into chips:**																					
8486.90.14	- - - - Tool holders and self-opening dieheads; work holders; dividing heads and other special attachments for machine tools	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.15	- - - - Other	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.16	- - - Of grinding, polishing and lapping machines for processing of semiconductor wafers	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.17	- - - Of apparatus for growing or pulling monocrystal semiconductor boules	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.19	- - - Other	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.9	**- - Of machines and apparatus for the manufacture of semiconductor devices or of electronic integrated circuits:**																					
8486.90.21	- - - Of chemical vapour deposition apparatus for semiconductor production	5%	5%	5%	5%	4%	4%	4%	3%	3%	3%	2%	2%	2%	1%	2%	0%	0%	0%	0%	0%	0%
8486.90.22	- - - Of epitaxial deposition machines for semiconductor wafers; of spinners for coating photographic emulsions on semiconductor wafers	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.90.23	- - - Of ion implanters for doping semiconductor materials; of apparatus for physical deposition by sputtering on semiconductor wafers; of physical deposition apparatus for semiconductor production; of direct write-on-wafer apparatus, step and repeat aligners and other lithography equipment	5%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%	0%
8486.9	**- - - Of spraying appliances for etching, stripping or cleaning semiconductor wafers; of apparatus for wet etching, developing, stripping or cleaning semiconductor wafers; of dry-etching patterns on semiconductor materials:**																					